

## System for Processing Materials Using Rapid Heating and Electric and Magnetic Fields

### **Disclosure Number**

201102612

### **Technology Summary**

The present invention comprises an apparatus and method that provide a novel way of processing thin films, thick films, coatings, and bulk materials in the presence of time varying electric and magnetic fields. The invention is suitable for processing materials in the liquid state, in the solid state and in mixed liquid-solid states. The invention can be used to control dispersions, microstructures, and other physical and chemical attributes of materials. The invention enables fast and relatively inexpensive processing of specialized materials such as, for example oxide dispersion strengthened alloys.

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